

JUN 15 2006

**PATENT**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In the **PATENT APPLICATION** of:

Ching-Wei Lin

**Application No.:** 10/767,665

**Confirmation No.:** 5412

**Filed:** January 29, 2004

**For:** PROCESS FOR FORMING  
POLYCRYSTALLINE SILICON LAYER BY  
LASER CRYSTALLIZATION

**Group:** 2813

**Examiner:** Stephen W. Smoot

Our File: TET-PT049

Date: June 15, 2006

**RESPONSE TO NON-COMPLIANT  
AMENDMENT PURSUANT TO 37 C.F.R. 1.121**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Enclosed is the signed amendment.

Respectfully submitted,

Ching-Wei Lin

By   
Stephen B. Schott  
Registration No. 51,294  
(215) 568-6400

Volpe and Koenig, P.C.  
United Plaza, Suite 1600  
30 South 17th Street  
Philadelphia, PA 19103

SBS/tab

JUN 15 2006

**PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the **PATENT APPLICATION** of:

Ching-Wei Lin

**Application No.:** 10/767,665**Confirmation No.:** 5412**Filed:** January 29, 2004For: PROCESS FOR FORMING  
POLYCRYSTALLINE SILICON LAYER BY  
LASER CRYSTALLIZATION**Group:** 2813**Examiner:** Stephen W. Smoot

Our File: TET-PT049

Date: June 15, 2006

**REPLY PURSUANT TO 37 C.F.R. § 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This Reply is being filed in response to the February 17, 2006 Office Action, and submitted with a petition for one month time extension; an earlier signed amendment was apparently not received by the USPTO.

Please amend the application without prejudice or disclaimer as follows.